

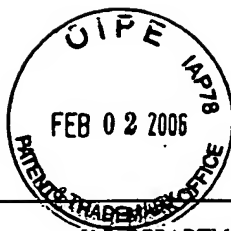
Sheet 1 of 2

Form PTO-1449 (Substitute)	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		Attorney Docket Number <b>TEGL-01168US0</b>	Application/Patent Number <b>10/636,020</b>
			Applicant/Patent Owner <b>Tue Nguyen</b>	
			Filing/Issue Date <b>August 7, 2003</b>	Group Art Unit <b>1734</b>

**Information Disclosure Statement**  
**BY APPLICANT**  
 (Use several sheets if necessary)

**U.S. PATENTS**

Examiner Initial	Patent Number	Issue Date	Inventor(s)	Class	Subclass	Filing Date
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